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TRANSMITTAL FORM

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TRANSMITTAL FORM (to be used for all correspondence after initial filing)	Application Number	10/769,149	
	Filing Date	January 30, 2004	
	First Named Inventor	Basceri et al.	
	Art Unit	1762	
	Examiner Name	Unknown	
Total Number of Pages in This Submission		Attorney Docket Number	MI22-2501

Total Number of Pages in This Submission

Attorney Docket Number

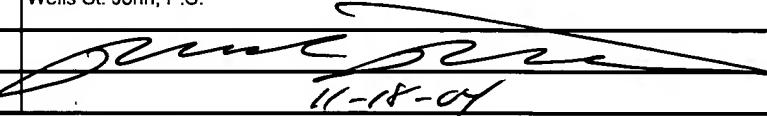
MI22-2501

ENCLOSURES (Check all that apply)

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Remarks		

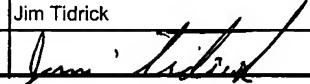
EV372470792

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm or Individual	Mark S. Malkin, Reg. No. 32,268 Wells St. John, P.S.
Signature	
Date	11-18-04

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/769,149
Filing Date January 30, 2004
Inventor Cem Basceri et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1762own
Examiner Unknown
Attorney Docket No. MI22-2501
Customer No. 021567
Title:Chemical Vapor Deposition Methods of Forming a Barium Strontium Titanate
Comprising Dielectric Layer Having a Varied Concentration of Barium and Strontium
With the Layer

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.

Pursuant to 1273 OG 55, August 5, 2003, no copies of cited U.S. patents or U.S. patent application publications are included, as the date of filing of this patent application occurs after June 30, 2003. Copies of all other art are attached hereto. No admission is made regarding whether all the listed references are prior art.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action on the merits, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

EV372470792

Respectfully submitted,

Dated: 10-18-04

By:



Mark S. Matkin
Reg. No. 32,268

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2501	SERIAL NO. 10/769,149
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Cem Basceri et al.	
		FILING DATE January 30, 2004	GROUP ART UNIT 1762

O P E R I C I O N S
PATENT & TRADEMARK OFFICE
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U.S. PATENT DOCUMENTS

*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,566,147 B2	05/2003	Basceri et al.			
	AB	4,261,698	04/1981	Carr et al.			
	AC	4,691,662	09/1987	Roppel et al.			
	AD	5,270,241	12/1993	Dennison et al.			
	AE	5,312,783	05/1994	Takasaki et al.			
	AF	5,392,189	02/1995	Fazan et al.			
	AG	5,395,771	03/1995	Nakato			
	AH	5,468,687	11/1995	Carl et al.			
	AI	5,261,961	11/1993	Takasu et al.			

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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ	0 030 798 A1	06/1981	EPO (Hughes Aircraft Company)			X	
	AK	GB 2 194 555 A	03/1988	UK (Nippon T & T Corporation)			X	
	AL	0 306 069 A2	03/1989	EPO (N.V. Phillips)			X	

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM		Stemmer et al., <i>Accommodation of nonstoichiometry in (100) fiber-textured (Ba_xSr_{1-x})Ti_{1+y}O_{3+z} thin films grown by chemical vapor deposition</i> , 74 APPL. PHYS. LETT., No. 17, pp. 2432-2434 (26 April 1999).
	AN		Streiffer et al., <i>Ferroelectricity in thin films: The dielectric response of fiber-textured (Ba_xSr_{1-x})Ti_{1+y}O_{3+z} thin films grown by chemical vapor deposition</i> , 86 J. APPL. PHYS. No. 8, pp. 4565-4575 (15 October 1999).
EXAMINER		DATE CONSIDERED	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,614,018	03/1997	Azuma et al.			
	AB	5,656,329	08/1997	Hampden-Smith			
	AC	5,663,089	09/1997	Tomozawa et al.			
	AD	5,702,562	12/1997	Wakahara			
	AE	5,719,417	02/1998	Roeder et al.			EY372470792
	AF	5,723,361	03/1998	Azuma et al.			
	AG	5,736,759	04/1998	Haushalter			
	AH	5,525,156	06/1996	Manada et al.			
	AI						

FOREIGN PATENT DOCUMENTS							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AJ	0 388 957 A2	09/1990	EPO (NEC Corporation)			X	
	AK	08-060347	03/1996	Japan (Fujitsu Ltd)			X	
	AL	EP 0 810 666 A1	12/1997	EPO (Oki Electric)			X	
	AM	JP2000091333 A	03/2000	Japan (Fujitsu Ltd)			X	
	AN	WO 01/16395 A1	03/2001	WIPO (Micron Technology)			X	
	AO	JP2250970	10/1990	Japan (NEC Corp.)			Abstract	
	AP	04-024922	01/1992	Abstract: Japan (Mitsubishi)			Abstract	

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)	
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U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,325,017 B1	12/2001	DeBoer et al.			
	AB	5,976,990	11/1999	Mercaldi et al.			
	AC	5,989,927	11/1999	Yamonobe			
	AD	6,101,085	08/2000	Kawahara et al.			
	AE	6,215,650	04/2001	Gnade et al.			EY372470792
	AF	6,258,654	07/2001	Gocho			
	AG	6,287,935 B1	09/2001	Coursey			
	AH						

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AI	EP 0 892 426 A2	01/1999	EPO (Ramtron International)			X
	AJ	0 474 140 A1	30.08.91	EPO (Kamiyama)			X
	AK	0 835 950 A1	13.10.97	EPO (Shinozaka et al.)			X
	AL	04-115533	04/1992	Abstract: Japan (OKI Electric)			Abstract
	AM	04-180566	06/1992	Japan (Matsushita Electric)			Abstract

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
AO		Aoyama et al., <i>Leakage Current Mechanism of Amorphous and Polycrystalline Ta₂O₅ Films Grown by</i>
		<i>Chemical Vapor Deposition</i> , 143 J. ELECTROCHEM SOC., No. 3, pp 977-983 (March 1996).
AP		Valiev et al., <i>Plastic deformation of alloys with submicron-grained structure</i> , MATERIALS SCIENCE AND
		ENGINEERING, A137, pp. 35-40 (1991).
EXAMINER		DATE CONSIDERED
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		